課題番号 :F-13-IT-0028

利用形態 :共同研究

利用課題名 (日本語) :W バンド MMIC 応用に向けた InxGa1-xAs メタモルフィック HEMTs の研究

Program Title (English) :Study of In_xGa_{1-x}As Metamorphic HEMTs for W-band MMIC Applications

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1. 概要(Summary)

The purpose of this research is to develop high frequency HEMT with good breakdown voltage for both power amplifier (PA) and low noise amplifier (LNA) applications. Optimized channel indium content, S-D spacing, gate-recess depth, and gate sinking was used to achieve V_{BD} over 5 V without large g_m degradation.

2. 実験 (Experimental)

The $0.09x20um^2$ devices with $In_{0.52}Ga_{0.48}As$ channel and L_{SD} of 3um were fabricated following typical HEMT process; fine gates exposures were obtained by e-beam lithography (JBX-6300 at Tokyo Tech).

3. 結果と考察(Results and Discussion)

The device exhibits I_{dss} =281 mA/mm and peak g_m = 604 mS/mm at V_{DS} = 0.7 V. The device also exhibits high V_{BD} of 5.88 V. This result is able to meet the requirements for both PA and LNA application.

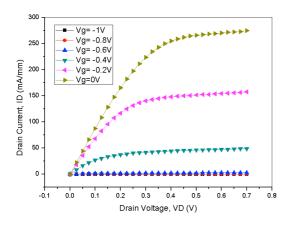


Fig. 1 Output characteristics.

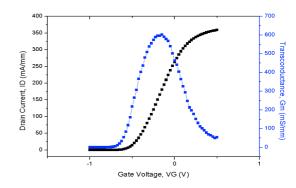


Fig. 2 Transfer characteristics.

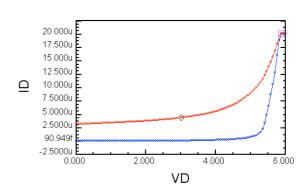


Fig. 3 Breakdown behavior.

4. その他・特記事項 (Others)

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5. 論文·学会発表(Publication/Presentation)

None

6. 関連特許 (Patent)

None